

In re the Application of: Kazuo TESHIROGI et al. Group Art Unit: 1733

Application Number: 10/718,653 Examiner: John L. Goff

Filed: November 24, 2003 Confirmation Number: 1182

For: FILM LAMINATION APPARATUS AND METHOD AND A

MANUFACTURING METHOD OF A SEMICONDUCTOR

APPARATUS

Attorney Docket Number: 032131

Customer Number: 38834

APPLICANTS' STATEMENT OF SUBSTANCE OF INTERVIEW

Mail Stop Amendment Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

April 16, 2007

Sir:

This paper is filed in response to the Examiner Interview Form (PTOL-413) dated March 20, 2007.

This paper is also filed to summarize an interview with the Examiner conducted on April 16, 2007.

On March 20, 2007 Applicants' representative and Examiner Goff discussed possible additional action by Applicants as accurately summarized by the Examiner in the Examiner Interview Form.

On April 16, 2007, Applicants' representative indicated to the Examiner that no additional response will be filed and requested that the Examiner consider Applicants' position as set forth in the Response filed March 6, 2007.

Applicants' Statement of Substance of Interview Application No. 10/718,653 Attorney Docket No. 032131

It is respectfully submitted that the instant APPLICANTS' STATEMENT OF SUBSTANCE OF INTERVIEW complies with the requirements of 37 C.F.R. §§1.2 and 1.133 and MPEP §713.04.

If this paper is not timely filed, Applicants respectfully petition for an appropriate extension of time. The fees for such an extension or any other fees that may be due with respect to this paper may be charged to Deposit Account No. 50-2866.

Respectfully submitted,

WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP

Ju (. Wright by. No. 41, 441

Michael J. Caridi Attorney for Applicants Registration No. 56171

Telephone: (202) 822-1100 Facsimile: (202) 822-1111

LCW/ya